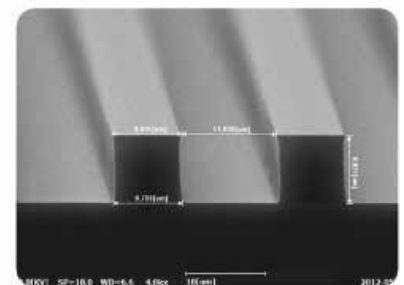
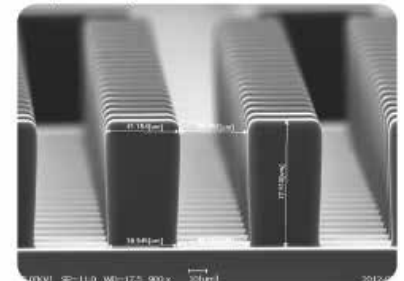


Manual Mask Aligner 4 inch

The MDA-400M is designed for research organizations who want to work with a state of the art technology mask aligner. This highly accurate system allows researchers to easily develop their processes on either small substrate pieces or wafers up to 4".



Standard Features

Manual control system

Sample size Up to 4" diameter

Mask holder size Up to 5"x 5"

UV lamp 350W

350W mercury short arc lamp & power supply

Dual CCD zoom microscope and 19" LCD monitor

Large area stationary alignment tooling module with X,Y,Z and theta motion

Wedge error compensation (leveling type)

Dimension 1000 (W) x 917 (D) x 781(H) mm

Weight 350 Kg

Warranty 1 year



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Manual Mask Aligner 4 inch

Light source module specifications

UV light source	350nm to 450nm
365nm intensity	20~30 mW/cm ²
Max. beam size	4.25" x 4.25"
Beam uniformity	3% (4"wafer)

Microscope specifications

Dual CCD zoom microscope with 19" LCD monitor	
Magnification	Monitor: 80x ~ 480x

Resolution specifications

Vacuum contact	1.0µm (Thin PR@Si Wafer)
Hard contact	1.5µm
Soft contact	2µm
20µm proximity	5µm

Utility requirement specifications

Electric power	230VAC / 50Hz / 15A / single phase with ground
Nitrogen	>40 psi (3 kg/cm ²), 6mm tube
Clean dry air	>85 psi (6 kg/cm ²), 6mm tube
Vacuum	< -200 mbar (vacuum pump included)

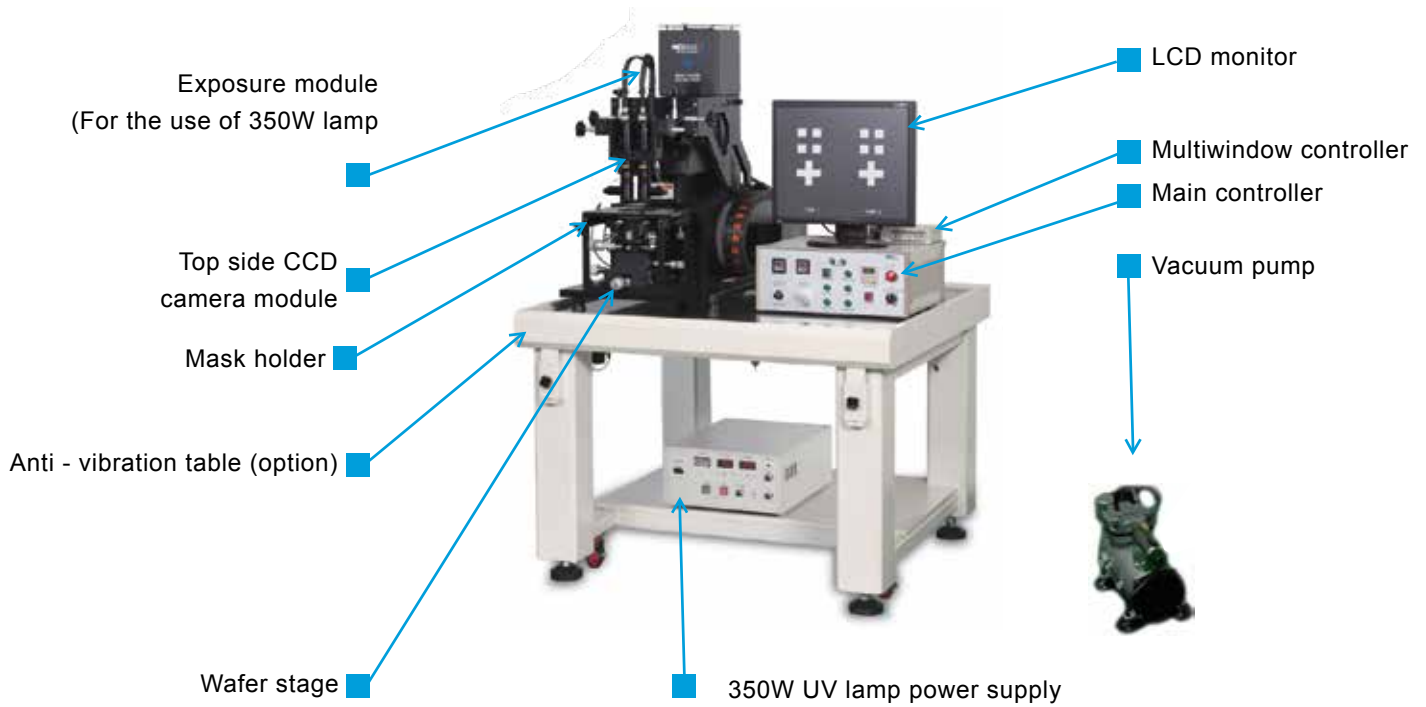
Stage and controller module specifications

Exposure timer	0.01 sec to 999.9 sec
Stage movement X, Y Z motion travel Theta	X, Y, Z and theta 10mm 15mm ±5°
Contact mode	Soft, vacuum, hard and proximity vacuum & hard contact force is adjustable
Alignment accuracy	<1.0µm
Vacuum / pneumatic controls	Substrate, mask, contact, chuck lock



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